

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of)
Hans-Joachim QUENZER et al.) Group Art Unit: Unassigned
Application No.: 09/889,956) Examiner: Unassigned
Filed: July 25, 2001)
For: METHOD FOR PRODUCING)
MICROMECHANICAL AND MICRO-)
OPTIC COMPONENTS CONSISTING OF)
GLASS-TYPE MATERIALS)

**INFORMATION DISCLOSURE STATEMENT
TRANSMITTAL LETTER**

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Enclosed is an Information Disclosure Statement and accompanying form PTO-1449 for the above-identified patent application.

- ☒ No additional fee for submission of an IDS is required.
- ☐ The fee of \$180.00 (126) as set forth in 37 C.F.R. § 1.17(p) is also enclosed.
- ☐ A certification under 37 C.F.R. § 1.97(e) is also enclosed.
- ☐ A certification under 37 C.F.R. § 1.97(e), and the fee of \$180.00 (126) as set forth in 37 C.F.R. § 1.17(p) are also enclosed.
- ☐ Charge \$_____ to Deposit Account No. 02-4800 for the fee due.
- ☐ A check in the amount of \$_____ is enclosed for the fee due.

The Commissioner is hereby authorized to charge any appropriate fees under 37 C.F.R. §§ 1.16, 1.17 and 1.21 that may be required by this paper, and to credit any overpayment, to Deposit Account No. 02-4800. This paper is submitted in duplicate.

Respectfully submitted,

BURNS, DOANE, SWECKER & MATHIS, L.L.P.

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By: Matthew L. Schneider
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Registration No. 32,814

Date: October 30, 2001

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INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents
Washington, D. C. 20231

Sir:

In accordance with 37 C.F.R. § 1.56, the following information is brought to the
Examiner's attention.

U.S. Patent No. 5,310,623. A discussion of relevance of this document is set forth
on page two of the present application.

The following six documents were cited during prosecution of a corresponding
German application.

U.S. Patent No. 5,623,368.

U.S. Patent No. 5,876,642.

European Patent Application No. 0 567 896.

Dong QUIN et al., "Microfabrication, Microstructures and Microsystems", *Topics in Current Chemistry*, Vol. 194, Microsystem Technology in Chemistry and Life Sciences, Springer Verlag, Berlin Heidelberg 1998, pages 1-20.

Jean SCHULZE et al., "Compact Self-Aligning Assemblies with Refractive Microlens Arrays Made by Contactless Embossing", *SPIE*, Vol. 3289, pages 22-32.

Thierry CORMAN et al., "Low-Pressure-Encapsulated Resonant Structures with Integrated Electrodes for Electrostatic Excitation and Capacitive Detection", *Sensors and Actuators A* 66, 1998, pages 160-166.

The following eight documents were cited in the International Search Report issued by the European Patent Office in connection with corresponding International Application No. PCT/EP00/11688. A copy of the International Search Report is enclosed.

International Publication No. WO 97/19027.

European Patent Application No. 0 690 028.

U.S. Patent No. 3,961,929.

U.S. Patent No. 4,883,525.

U.S. Patent No. 4,883,524.

U.S. Patent No. 5,122,176.

European Patent Application No. 0 493 202.

Offenlegungsschrift No. 1 596 490.

To assist the Examiner in entering the foregoing information into the record, the above-noted documents are cited on the attached form PTO-1449 and copies of the documents are enclosed.

The Examiner is respectfully requested to consider the foregoing information and to acknowledge such consideration by initialling, signing and returning the enclosed additional copy of form PTO-1449.

Respectfully submitted,

BURNS, DOANE, SWECKER, & MATHIS, L.L.P.

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Date: October 30, 2001

Substitute for form 1449A/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

ATTORNEY'S DKT NO.
033033-002

APPLICATION NO.
09/889,956

APPLICANT
Hans-Joachim QUENZER et al.

FILING DATE
July 25, 2001

GROUP
Unassigned

U.S. PATENT DOCUMENTS

Examiner Initials	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication (MM-DD-YYYY)
	Number	Kind Code (if known)		
	5,310,623	A	GAL	5/10/1994
	5,623,368	A	CALDERINI et al.	4/22/1997
	5,876,642	A	CALDERINI et al.	3/02/1999
	3,961,929		STOCKDALE	6/08/1976
	4,883,525		BUCKLEY et al.	11/28/1989
	4,883,524		BRISTOL	11/28/1989
	5,122,176	A	GOETTLER	6/16/1992

FOREIGN PATENT DOCUMENTS

Examiner Initials	Foreign Patent Document		Country	Date of Publication (MM-DD-YYYY)	Translation	
	Number	Kind Code (if known)			Yes	no
	0 567 896	A1	EUROPE	11/03/1993		
	97/19027	A1	INTERNATIONAL	5/29/1997		
	0 690 028	A1	EUROPE	1/03/1996		
	0 493 202	A1	EUROPE	7/01/1992		
	1 596 490		GERMANY	5/19/1971		

NON PATENT LITERATURE DOCUMENTS

Examiner Initials	Include name of author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.
	Dong QUIN et al., "Microfabrication, Microstructures and Microsystems", <i>Topics in Current Chemistry</i> , Vol. 194, <i>Microsystem Technology in Chemistry and Life Sciences</i> , Springer Verlag, Berlin Heidelberg 1998, pages 1-20.
	Jean SCHULZE et al., "Compact Self-Aligning Assemblies with Refractive Microlens Arrays Made by Contactless Embossing", <i>SPIE</i> , Vol. 3289, pages 22-32.
	Thierry CORMAN et al., "Low-Pressure-Encapsulated Resonant Structures with Integrated Electrodes for Electrostatic Excitation and Capacitive Detection", <i>Sensors and Actuators A</i> 66, 1998, pages 160-166.
Examiner Signature	Date Considered

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. SEND TO: Assistant Commissioner for Patents, Washington, D.C. 20231.